

MICROFABRICATION

SEM / FIB Microscope

Manufacturer: Thermo Fisher

Model: Helios G4 UC



General Description:

The Helios G4 is a combined electron / focused ion beam microscope for topography and morphology analysis of micro- and nanostructures as well as the structuring of thereof. The system is equipped with a Bruker EDX detector, which allows to determine the composition of chemical elements in a sample.

Key Specifications:

- Up to 200 mm wafers
- High resolution SEM imaging
- Electron column and Ion column (Ga-Ions) up to 30 kV
- Ion beam patterning
- Gas injection system for Pt deposition and insulator enhanced etch (XeF₂)
- SE detectors: ETD, TLD
- BSE detectors: TLD, MD, ICD, ABS, CBS
- EDX detector
- Software: XT microscope, Maps plugin, Nanobuilder plugin

Availability	Use allowed for all researchers with permission
Location	Cleanroom C8 Europastraße 12 9524 Villach
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